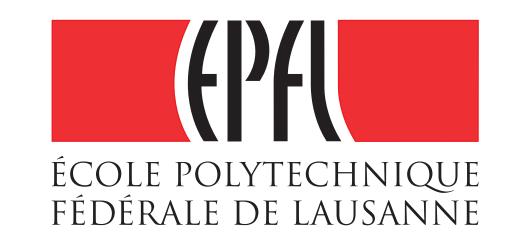
BIORESORBABLE FREQUENCY-SELECTIVE MAGNESIUM MICRO-**RESONATORS FABRICATED BY ION BEAM ETCHING**



100 µm

4 um

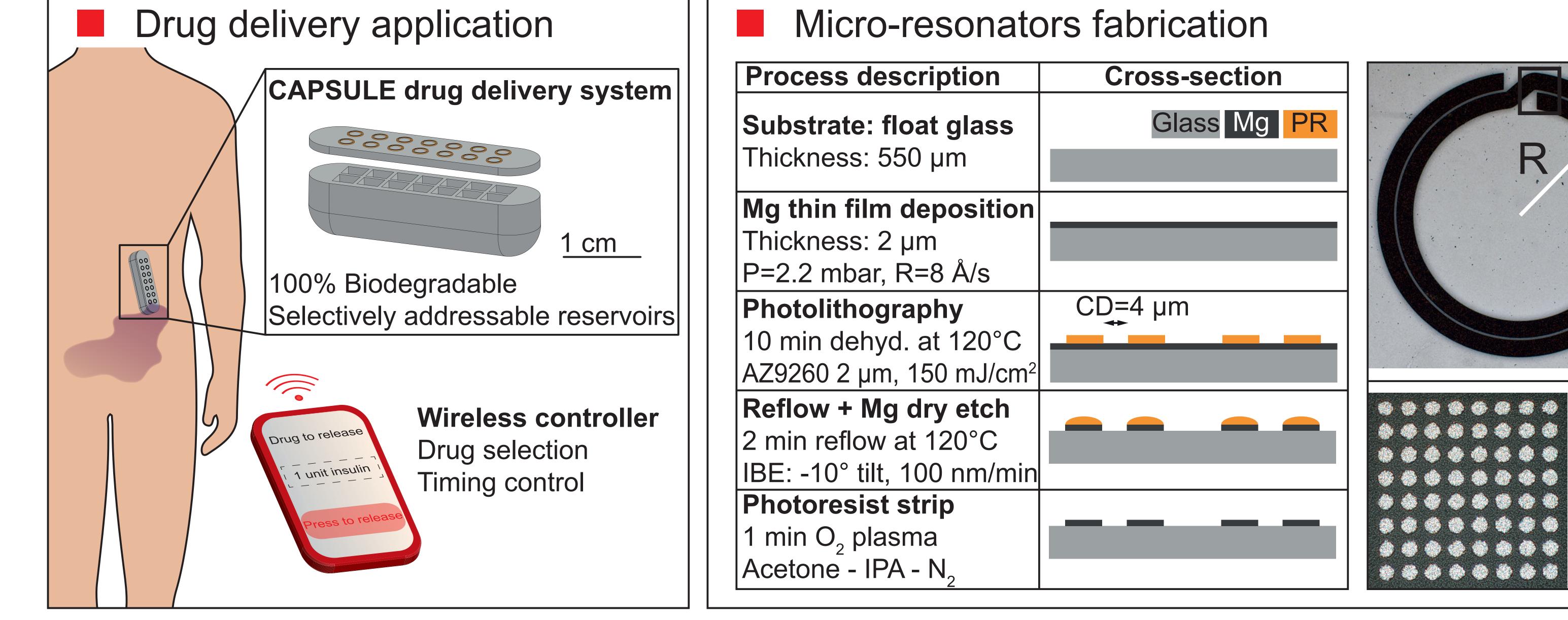
 $20\,\mathrm{um}$

Matthieu Rüegg, Remo Blum, Giovanni Boero, Jürgen Brugger

Microsystems Laboratory, Ecole Polytechnique Fédérale de Lausanne, 1015 Lausanne, Switzerland



We present an innovative microfabrication process to fabricate magnesium-based bioresorbable microelectromechanical systems (MEMS) by ion beam etching. This process enables the fabrication of thin biodegradable water-soluble passive electronic components with minimal exposure to aqueous media, by a novel physical vapor deposition, photolithography and dry etching sequence. We demonstrate the design, fabrication and characterization of frequency-selective magnesium RF micro-resonators in air and in water, and compare the results to values obtained by finite element modeling (FEM). Such resonators are candidates for selectively-addressable RF power receivers for bioresorbable wireless implantable medical devices.





CHARLES CONTRACTOR

Micro-resonators characterization

Resonance frequencies for different designs

FEM for resonators with and without meander

